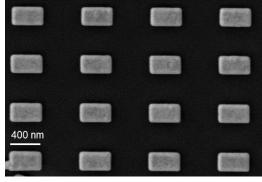
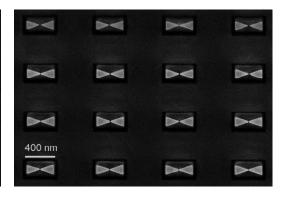
Figure 1: Stepwise fabrication of nano bowties in 50nm Au film on Si

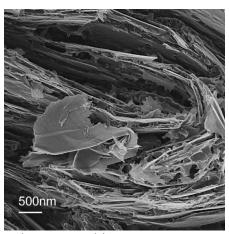


Step 1: Bi FIB for large volume milling at high sputter yield to excavate rectangular boxes.

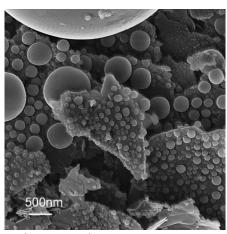


Step 2: Li FIB for fine shaping of rectangular boxes to fabricate bowties structures at highest resolution.

Figure 2: *Lithium-ion images* 



Substrate graphite



Substrate Sn/C